



Atty. Dkt. No.	M#	Client Ref.
081468	0309196	P-1851.000-US
Applicant: Aleksey Yurievich KOLESNYCHENKO, et al.		
Appln. No.: 10/823,777		
Filing Date: April 14, 2004		
Examiner: GUTIERREZ, Kevin C.		Group Art Unit: 2851

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YYR				Enclosed	No
ZZR				Enclose	No
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	HHHHR						
	IIIIIR						
	JJJJR						
	KKKKR						
	LLLLR						
	MMMMR						
	NNNNR						
	OOOOR						
	PPPPR						

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							Enclosed	No
	QQQQR							
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